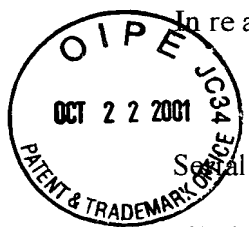


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re application of:

Mamoru NAKASUJI, et al.

ATTN: Box Missing Parts

Serial No.: 09/891,511

Group Art Unit: Unknown

Filed: June 27, 2001

Examiner: Unknown

For: INSPECTION SYSTEM BY CHARGED PARTICLE BEAM AND METHOD OF
MANUFACTURING DEVICES USING THE SYSTEM

AMENDMENT TRANSMITTAL

Commissioner for Patents
Washington, D.C. 20231

October 22, 2001

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below:

	CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid For		Present Extra	Large Entity	Additional Fee
Total Claims	110	20	=	90	X \$18	\$ 1,620.00
Independent Claims	13	3	=	10	X \$84	\$ 840.00
XX First Presentation of Multiple Dependent Claims					\$280	\$ 280.00
TOTAL FEES ENCLOSED:						\$ 2,740.00

X Enclosed please find our check in the amount of \$ 2,740.00 for the additional claims fee in connection with this amendment. The Commissioner is hereby authorized to charge payment for any additional fees associated with this communication or credit any overpayment to Deposit Account No. 01-2340. Two duplicates of this sheet are attached.

Respectfully submitted,

ARMSTRONG, WESTERMAN, HATTORI
MCLELAND & NAUGHTON, LLP

William G. Kratz, Jr.
Attorney for Applicants
Reg. No. 22,631

Attorney Docket No.: 010819
1725 K Street, N.W.
Suite 1000
Washington, D.C. 20006
Tel: (202) 659-2930
WGK/sdj

#6
Pre-Amended
Division
4-4-02



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Mamoru NAKASUJI, et al.

ATTN: Box Missing Parts

Serial No.: 09/891,511

Group Art Unit: Unknown

Filed: June 27, 2001

Examiner: Unknown

For: INSPECTION SYSTEM BY CHARGED PARTICLE BEAM AND METHOD OF
MANUFACTURING DEVICES USING THE SYSTEM

PRELIMINARY AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Date: October 22, 2001

Sir:

Prior to calculation of the filing fee and examination of this application, please amend the
above-identified application as follows:

10/25/2001 BABRANA1 00000011 03891511

01 FC:103
02 FC:102
03 FC:104

162 1 01
340 1 01
280.00 01

IN THE CLAIMS:

Please amend claims 16, 25, 30, 44-49, 54 and 59 as follows:

16. (Amended) A method of manufacturing a device comprising the steps of:

detecting defects on a wafer using an inspection apparatus according to any one
of claims 1 to 5 in the middle of a process or subsequent to the process.

25. (Amended) A defect inspection apparatus using the E x B separator defined by

any of claims 21 to 23, in which:

162 1 01
340 1 01
280.00 01

162 1 01
340 1 01
280.00 01
50.00 01

162 1 01
340 1 01
280.00 01
50.00 01

162 1 01
340 1 01
280.00 01
50.00 01